



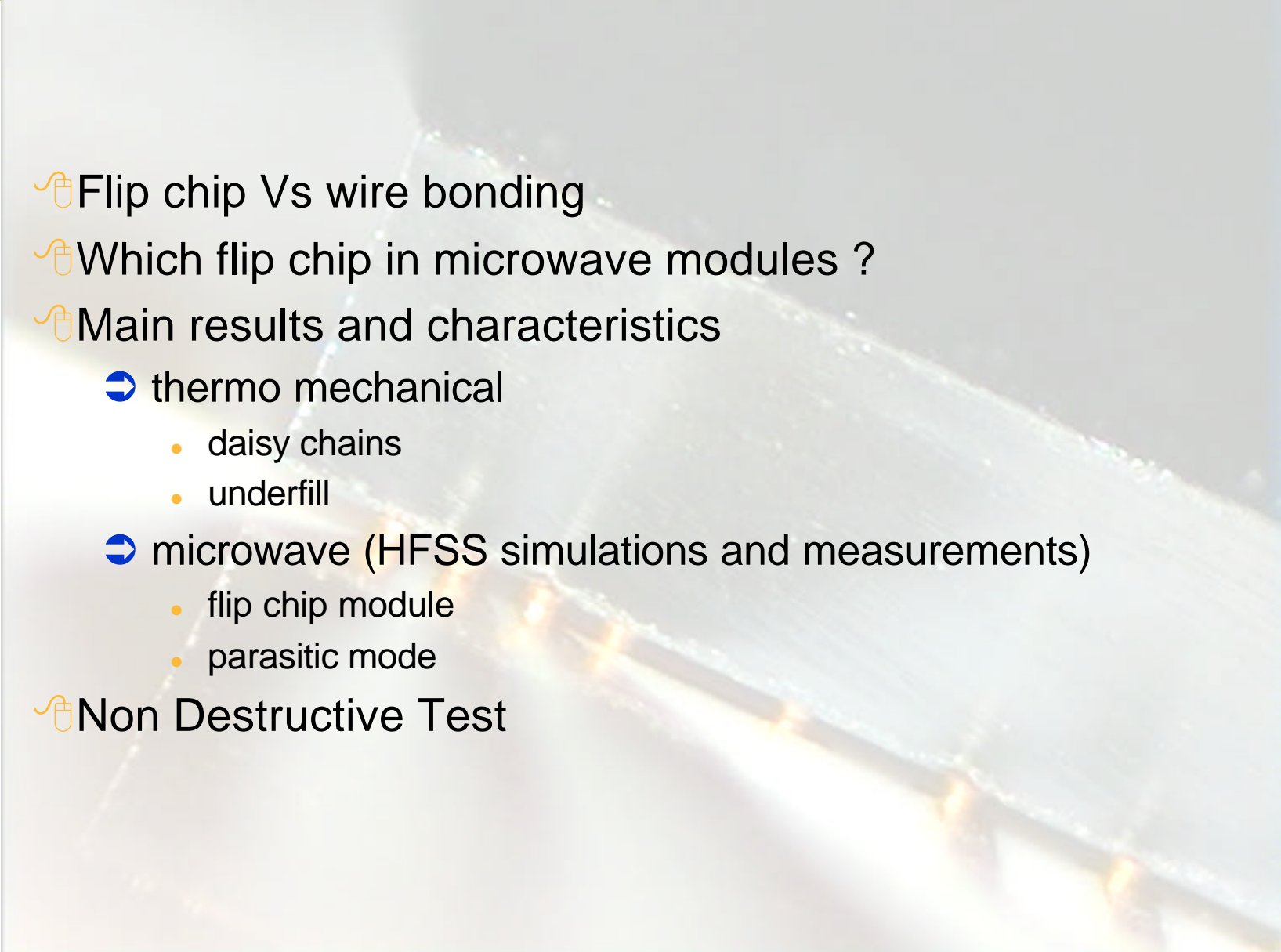
Flip Chip for microwave applications



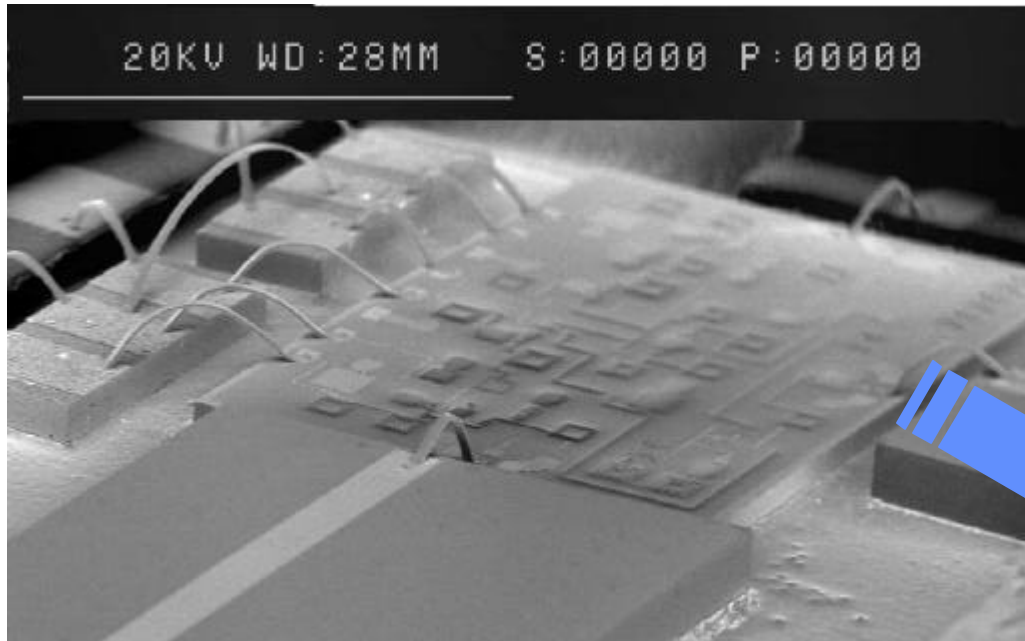
Alcatel Space - Toulouse - France

C. Schaffauser - C. Drevon

Flip Chip for microwave applications

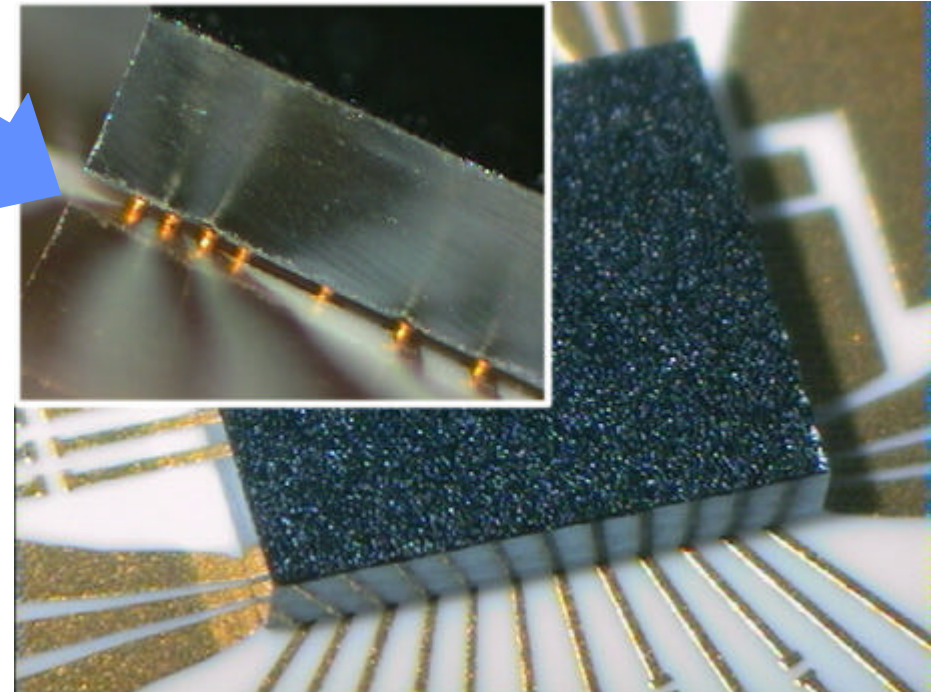
- 
- ✎ Flip chip Vs wire bonding
 - ✎ Which flip chip in microwave modules ?
 - ✎ Main results and characteristics
 - ➔ thermo mechanical
 - daisy chains
 - underfill
 - ➔ microwave (HFSS simulations and measurements)
 - flip chip module
 - parasitic mode
 - ✎ Non Destructive Test

Wire bonding towards flip chip



mechanical interface : glue
electrical interface : glue and wires

Only one mechanical and electrical interface : bumps



Flip Chip or Gluing&Wire bonding ?

◆ Cons Flip Chip

Electrical

- ➔ the back of the die must be well connected to ground

Fabrication

- ➔ "new" process (gluing and wire bonding still present)
- ➔ Control is more difficult and visual inspection is impossible after assembly

◆ Pros Flip Chip

Electrical

- ➔ better RF performances
- ➔ perfect for reaching higher frequencies
 - better performances
 - wider frequency bandwidth (less selective)
- ➔ more repetitive results

Alcatel Flip Chip Needs

◆ When wire bonding assembly is limited

🖱️ for power applications,

- ➡️ when heat dissipation through GaAs is not enough,
 - thermal bumps near transistor hot parts

🖱️ For millimetre wave applications

- ➡️ when bonding 2 or 3 wires in parallel is not sufficient for good S11,
- ➡️ when parasitic effect of wires can not be cancelled any more,
 - need for thin and high bumps

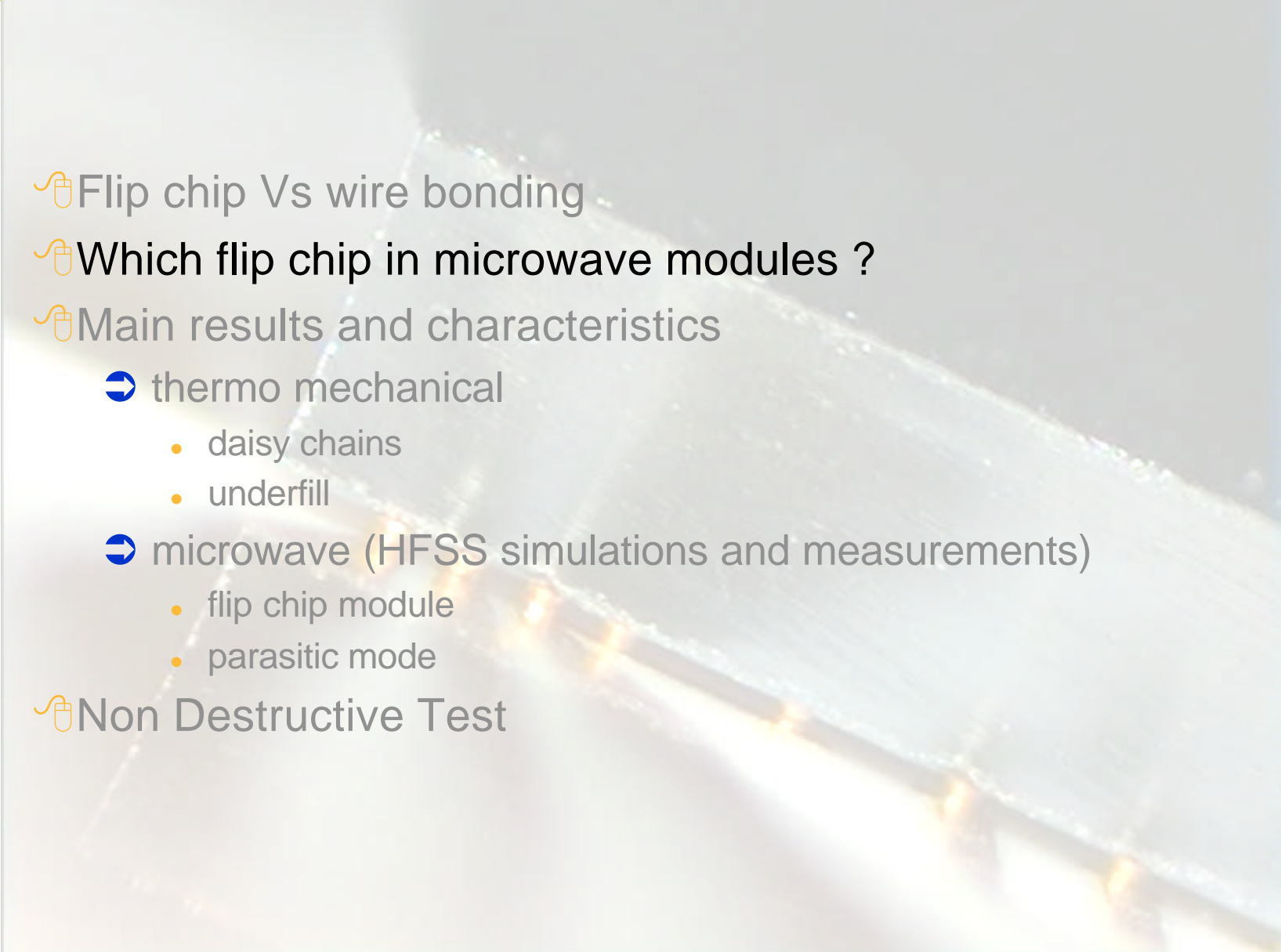
◆ Quality Insurance

🖱️ Thermal Expansion Coefficient difference between die and substrate can quickly create failure

- ➡️ Need for underfill ? Which underfill ?
- ➡️ Verification with thermal cycles

🖱️ Non destructive Control ?

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RF application particularities

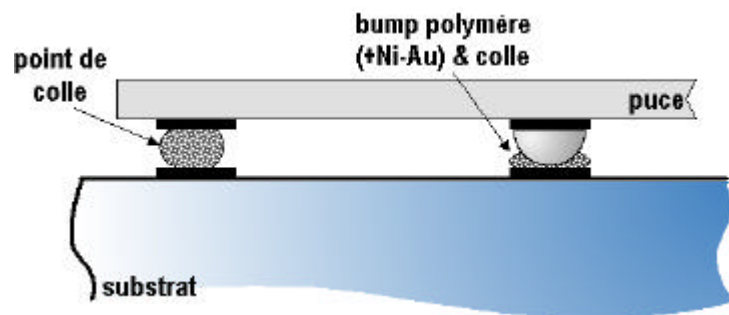
- ✎ GaAs components (usually 100 μm thick)
- ✎ a few bumps : 10 to 20 per die
- ✎ pad dimensions and pitch : 50 to 100 μm - Au top metallization

in a flip chip configuration

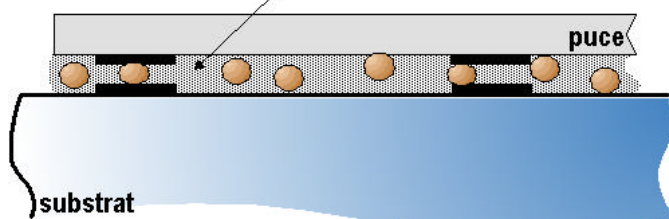
- ✎ Die active face down facing the substrate
 - ➡ package influence on RF performances
 - material electrical characteristics (dielectric constant, losses...)
 - ground plane position, connection, quality and proximity,
 - gap height between die and substrate...
- ✎ most of the time : microstrip access on substrate and ground plane just beneath

Which Flip Chip for microwave applications ?

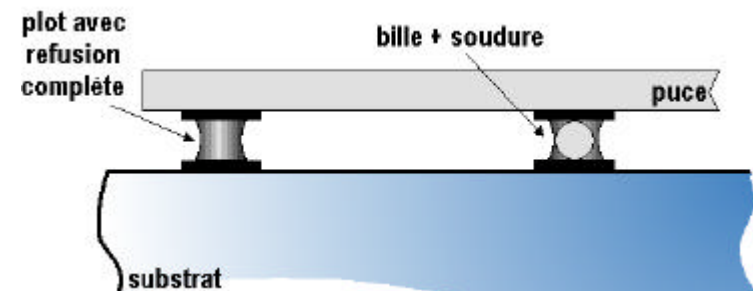
Gluing



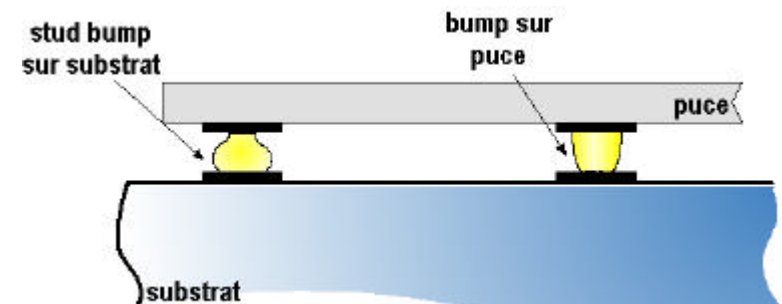
colle anisotropique
(matrice époxy + billes conductrices)



Soldering



Thermo-compression



◆ Alcatel Space hyper frequency dice are GaAs dice with gold pads

🖱 Soldering ?

- ➡ no SnPb solder directly on die
- ➡ AuSn would be more appropriate
 - quite high temperature process

🖱 Gluing ?

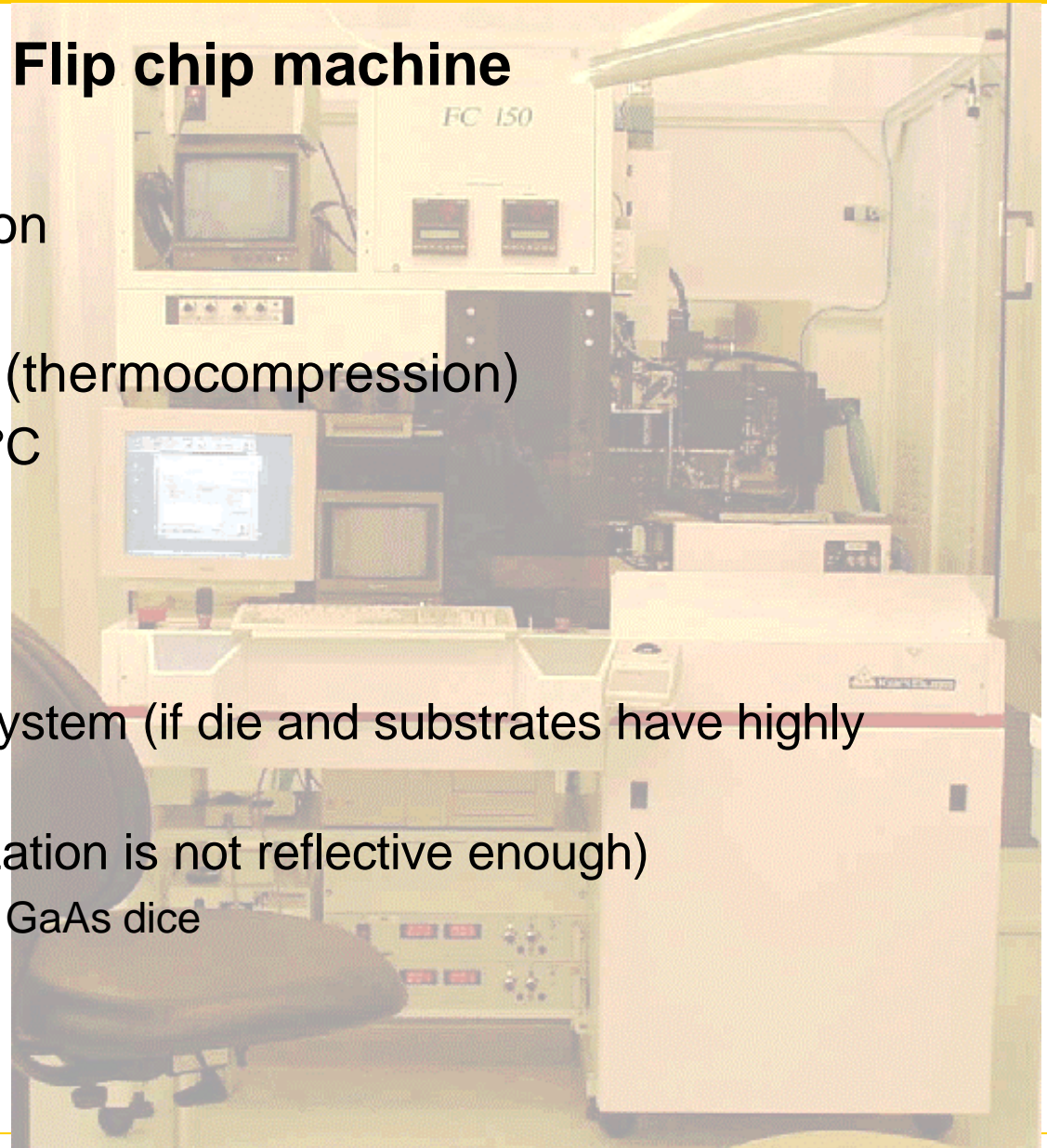
- ➡ Is one solution when low temperature process is needed (ex : organic parts)
- ➡ still need small pitches and thin and high bumps
 - gold bumps too
 - not compatible with usual gluing techniques
- ➡ Compatible with Silicon and GaAs pads

🖱 Thermocompression ?

- ➡ Alcatel Space main experience
- ➡ compatible with gold pads and their small dimensions and pitches
- ➡ but high temperature process
 - gold bumps

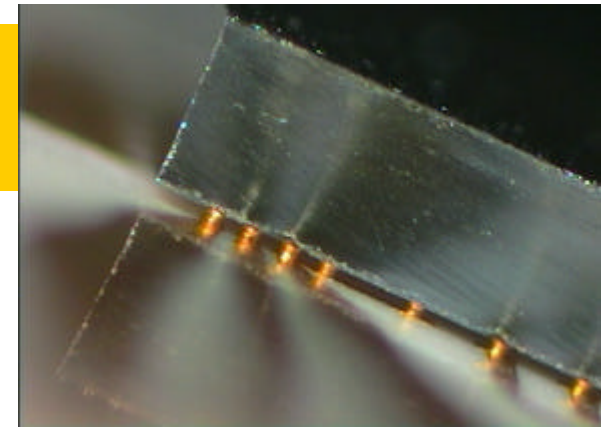
Suss Microtec Flip chip machine

- 🖱 Thermocompression or refusion
 - ➡ depends on used arm
- 🖱 3 μm XY precision at 3 sigma (thermocompression)
 - ➡ maximum temperature : 450°C
 - ➡ Maximum Load : 50 Kgf
- 🖱 Parallelism correction :
 - ➡ with optical autocollimation system (if die and substrates have highly reflective metallization)
 - ➡ with Laser system (if metallization is not reflective enough)
 - most of the time the case with GaAs dice



Flip Chip for microwave applications

Flip Chip under study at Alcatel Space



🖱️ **Power Flip Chip**

- ➡ Gold thermal bumps made on wafer (by the foundry)
- ➡ High Thermal dissipation substrate (AlN, Diamond...) with thin film and via

🖱️ **Low Power Flip Chip**

- ➡ Gold stud bumps (3 possible heights) made by HCM La Rochelle
- ➡ Al_2O_3 substrate with thin film and via

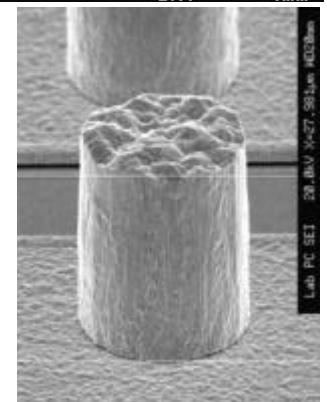
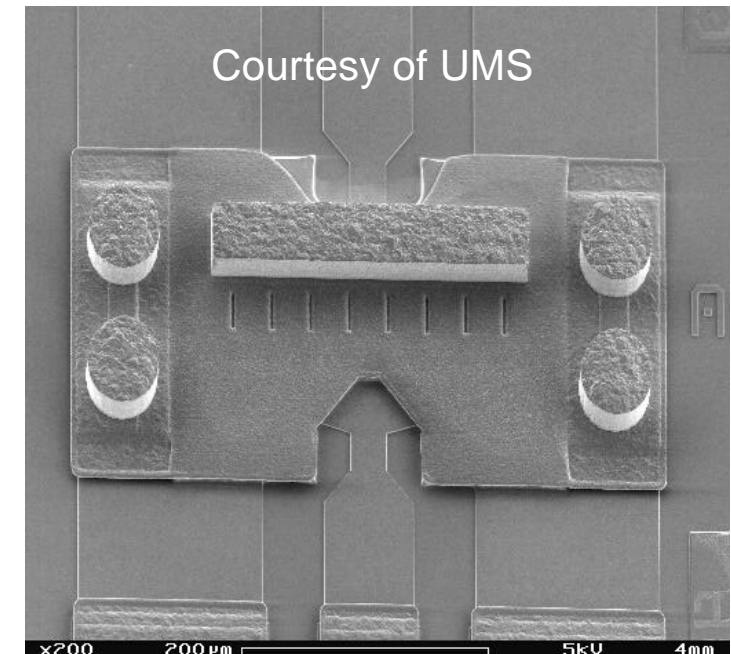
🖱️ **Possible "dice" : MMIC, transistors, MEMS**

🖱️ **Mostly used technique : thermocompression**

"Power Applications"

Electrolytic Bumps

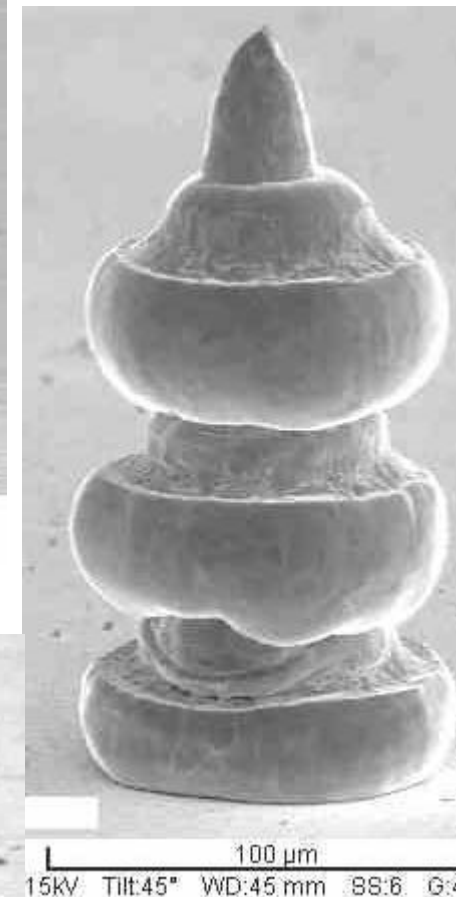
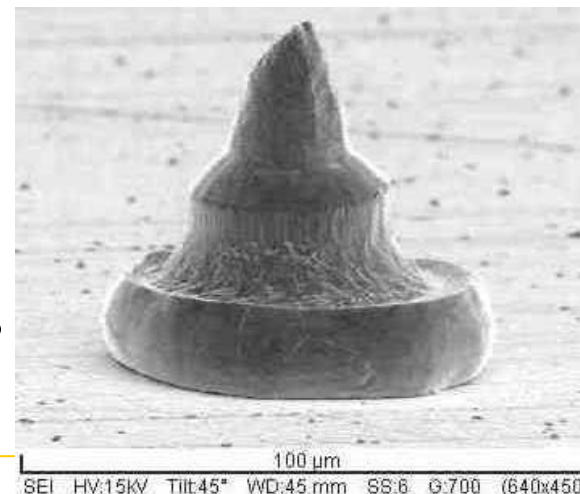
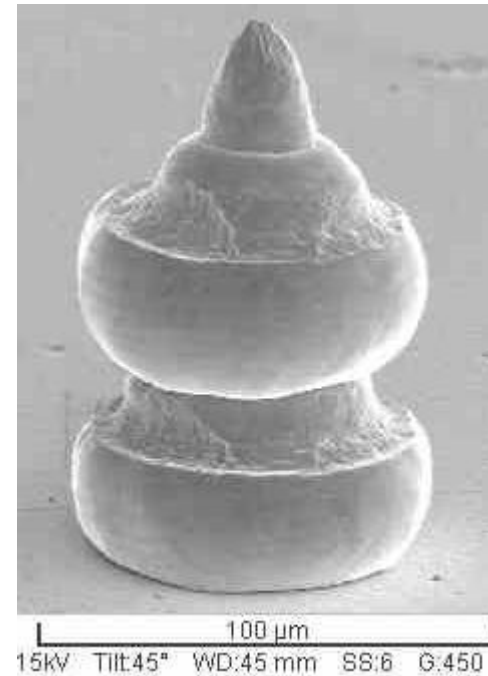
- 🖱️ Made on the wafer (by the MMIC foundry)
 - ➡ perfect for mass production
 - ➡ gold electrolytic growth
 - Height \leq Diameter
 - ➡ Excellent for thermal dissipation
 - Thermal bumps on the hottest points of the transistors
 - ➡ Critical Points
 - How to perform electrical tests ?
 - No proper evaluation due to bump fabrication default
- 🖱️ Some foundries can make those bumps on GaAs, GaN, SiC wafers



Courtesy
of UMS

"Standard Applications" Stud Bumps

- 🖱️ Made on substrate
 - ➡ can use MMICs of the shelves
- 🖱️ Adapted to both RF and LF part dimensions
 - ➡ 60 μ m diameter
- 🖱️ Several possible heights
 - ➡ 20 to 90 μ m
- 🖱️ Very good adhesion on AlN and Alumina substrates
 - ➡ around 20gf per bump
- 🖱️ Evaluation performed on HCM bumps
 - ➡ ESTEC Study (2004)



Stud Bump Theory

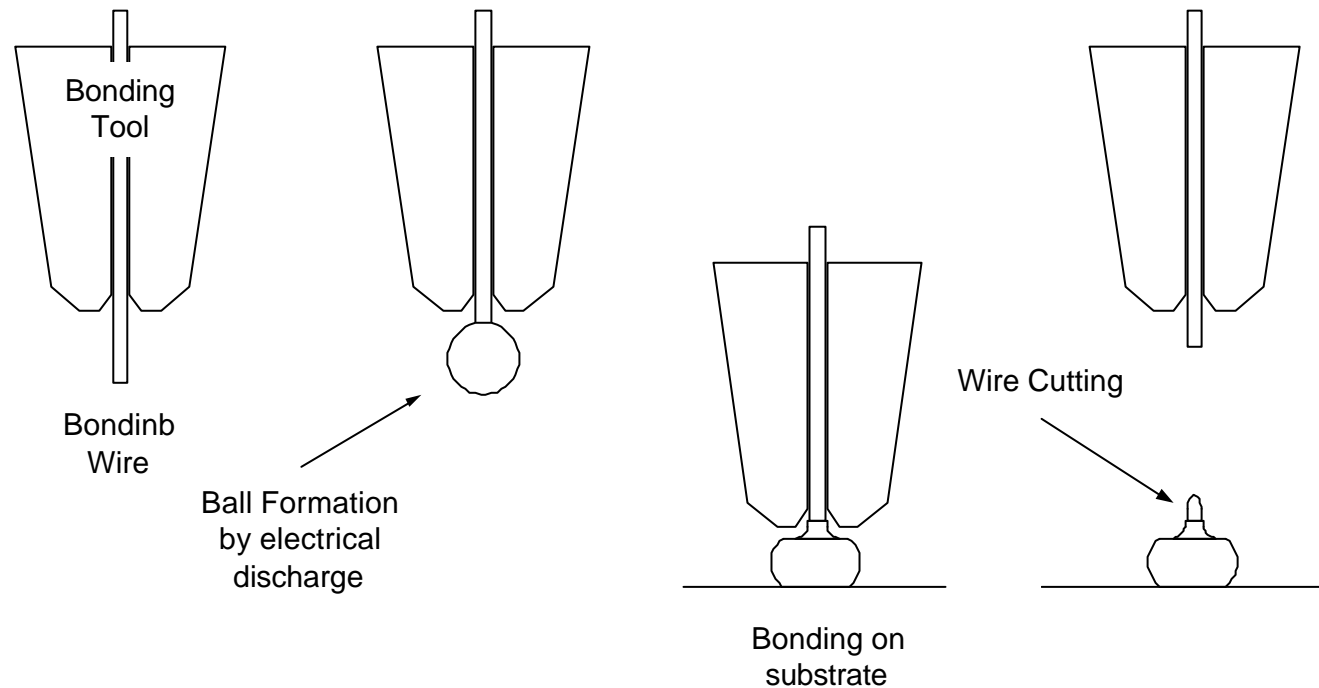
◆ Two ways of performing stud bumps

🖱️ 1 - PANASONIC patent

- ➡ gold wire used for wire bonding (same gold)
- ➡ wire cutting by a quick movement of bonding tool - wire torsion
- ➡ stitch against the ball

🖱️ 2 - HCM bumps

- ➡ wire pulling until break
- ➡ dedicated gold wire (1 or 2% palladium for wire breaking)
- ➡ usually 20 μm diameter wires, could be 17.5 μm



HCM Stud Bumps possibilities

- ◆ HCM La Rochelle France - Micro electronic Packaging
- ◆ Design rules
 - ✎ **+/- 3,5 μm** accuracy with K&S8028 machine
 - ✎ Minimum pitch between bumps : **55 μm**
 - ✎ Minimum pad dimension : **50 μm**
- ◆ Gold wire
 - ✎ AW6 type gold wire with Pd - **20 μm** diameter
 - ✎ can have **18 μm** diameter
- ◆ Machine and tools
 - ✎ K&S1484 usual machine
 - ✎ K&S 8028PPS new machine
 - ✎ Many tools can be used but difficult to test them all.

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 - flip chip module
 - parasitic mode
 - ✎ Non Destructive Test

Flip Chip for microwave applications

Process quality and reliability

🖱 When optimising a process, one must check its quality and strength

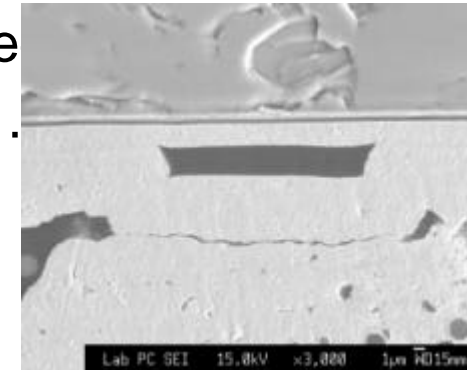
- ➡ just after assembly : see if all bumps are correctly connected
- ➡ after ageing tests : see if bumps stay correctly connected...

🖱 Possible defaults

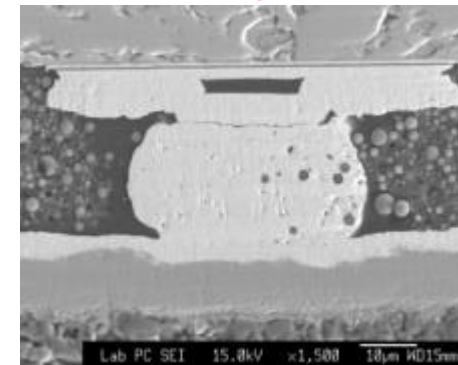
- ➡ Too much strain between die and substrate (due to Coefficient of Thermal Expansion mismatch and big dice)
 - délamination between bump and pad
- ➡ Pollution
 - no bump adhesion on pad
- ➡ Air trapped inside underfill (if there is some)
 - if those bubbles are against bumps, it might concentrate stress on those bumps

🖱 Checking techniques

- ➡ Cut / SEM / EDAX -> long and expensive
- ➡ Daisy Chain and 4-point resistance measurement



Fabrication default o bumps made on the wafer by UMS



Daisy Chain Resistance Measurement

- ◆ The best way to control assembly quality and reliability
 - 🖱️ precise and complete information on contacts at initial time & during ageing
 - 🖱️ to see the impact of chosen materials, dimensions...on assembly sturdiness
 - 🖱️ to find the weakest parts of assemblies
- ◆ ASP has a dedicated test bench - 4 point resistance measurement
 - 🖱️ easy adaptation to different dice, assemblies...
 - 🖱️ 5% precision on a 1mΩ resistance
 - ➡ very precise measurement of bump evolution
 - 🖱️ automatic measurement of entire daisy chain and small parts of it
 - ➡ some defaults appear and progress very slowly
 - ➡ one bump default could stay a long time unnoticed as bump resistance variation would stay very small compared to the whole chain resistance

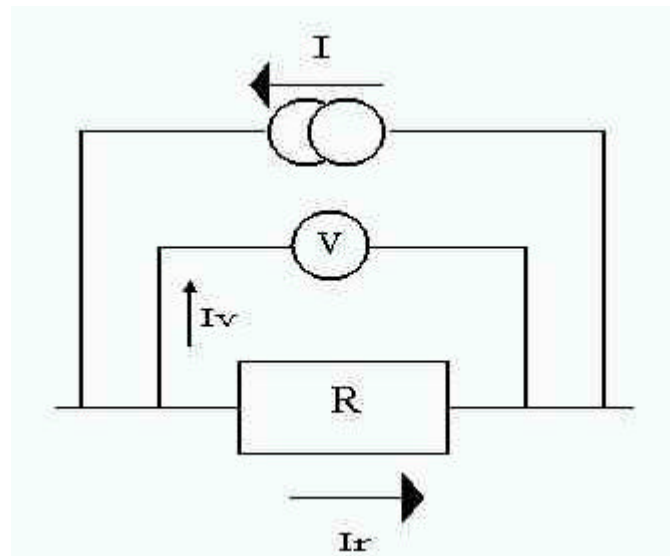
◆ 4 point resistance measurement

🖱️ Theory

$$I_r \gg I$$

$$I_v \ll I_r$$

- ➡ So measured resistance is nearly exact R
- ➡ Wires and lines that bring current or that measure voltage are not taken into account
- ➡ and moreover, any ΔR will be more easily noticed



◆ Bump pairs - ordinary daisy chains

🖱 bumps are connected with lines alternately on die and substrate

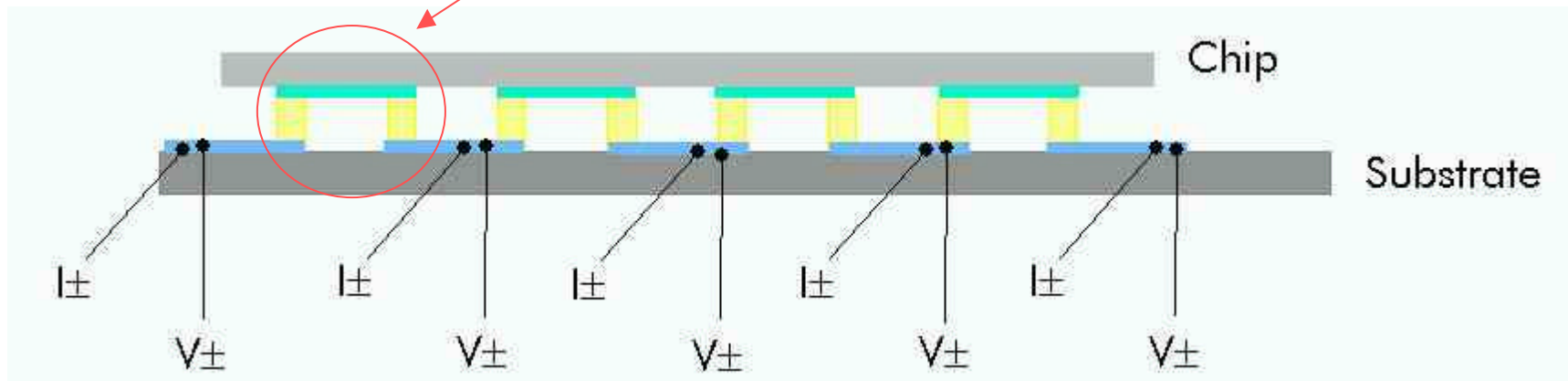
➡ the total length of the daisy chain can be measured

- immediate indication of failure
- but not always information on default apparition

➡ or we can measure groups of "Two bumps and a line on die"

- Measured resistance is smaller so one bump evolution should be visible
- location of the default

🖱 very simple principle and measurement



Flip Chip for microwave applications

Thermo mechanical

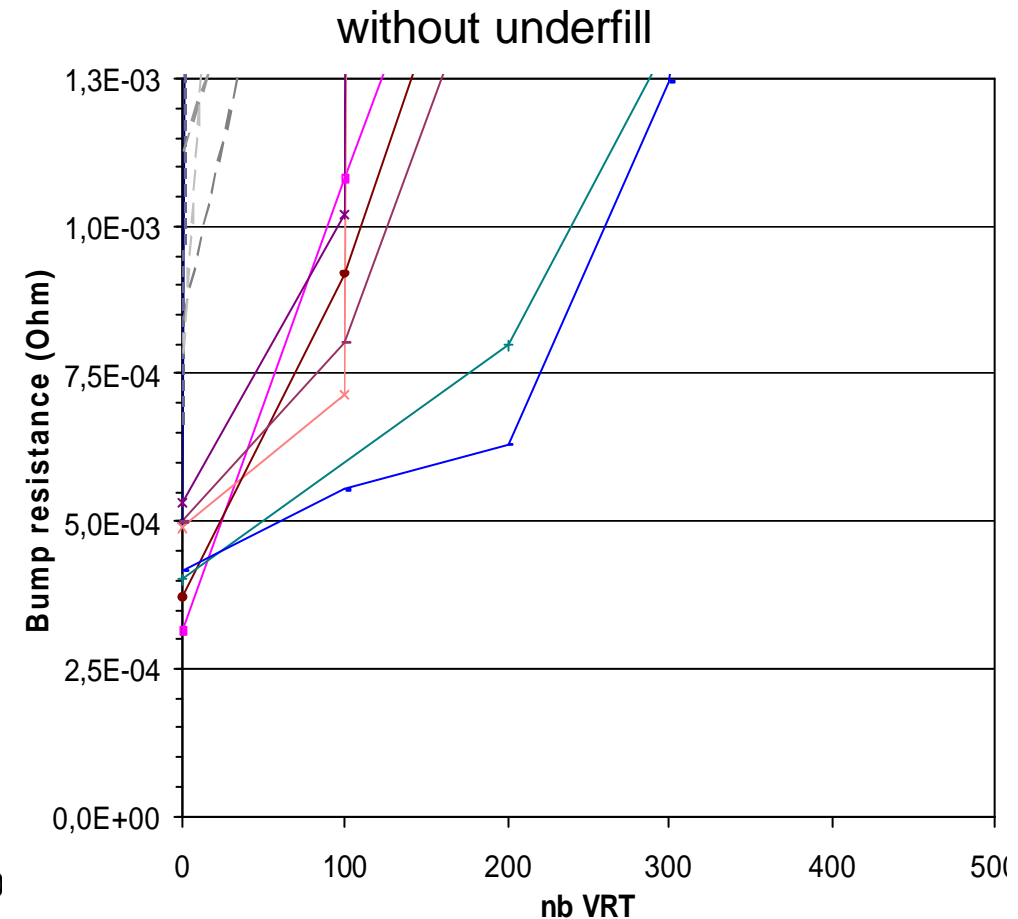
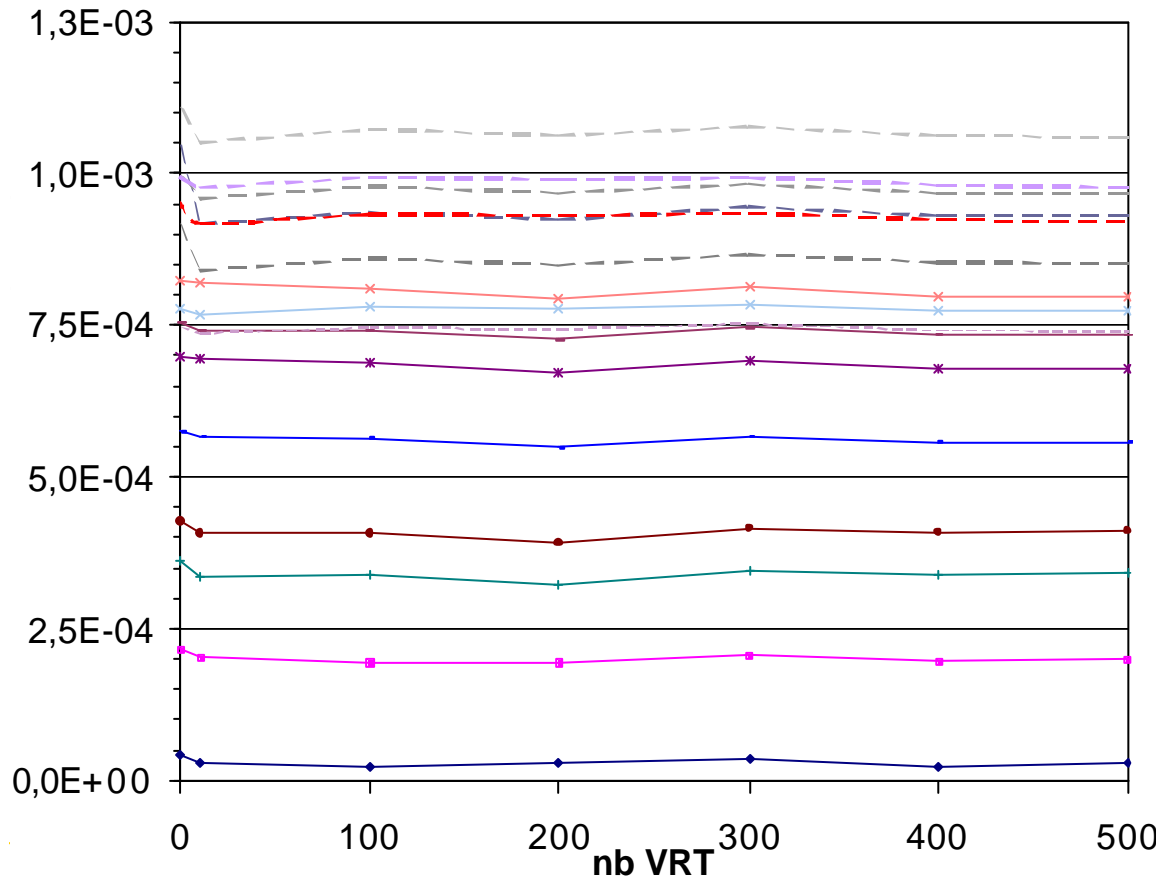
◆ Some results with GaAs on alumina and AlN

🔧 Thermocompression process

🔧 Thermal cycling

➡ On AlN

● with underfill



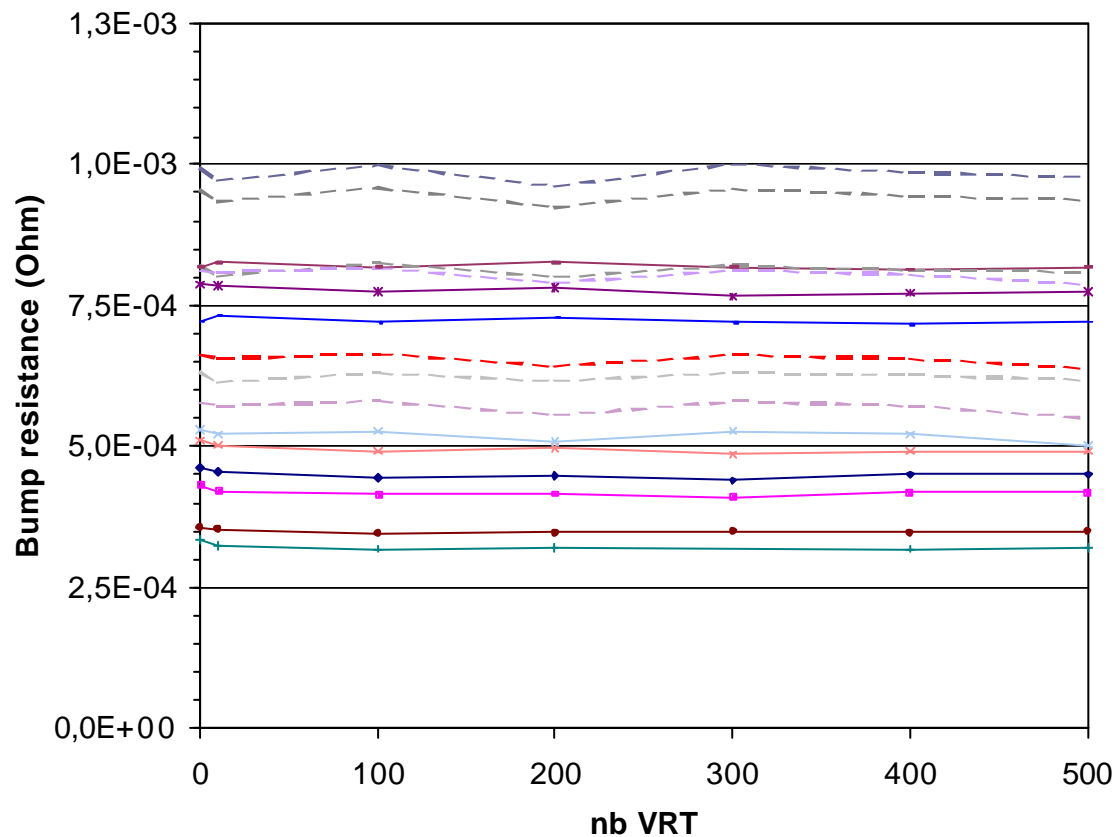
Flip Chip for microwave applications

Thermo mechanical

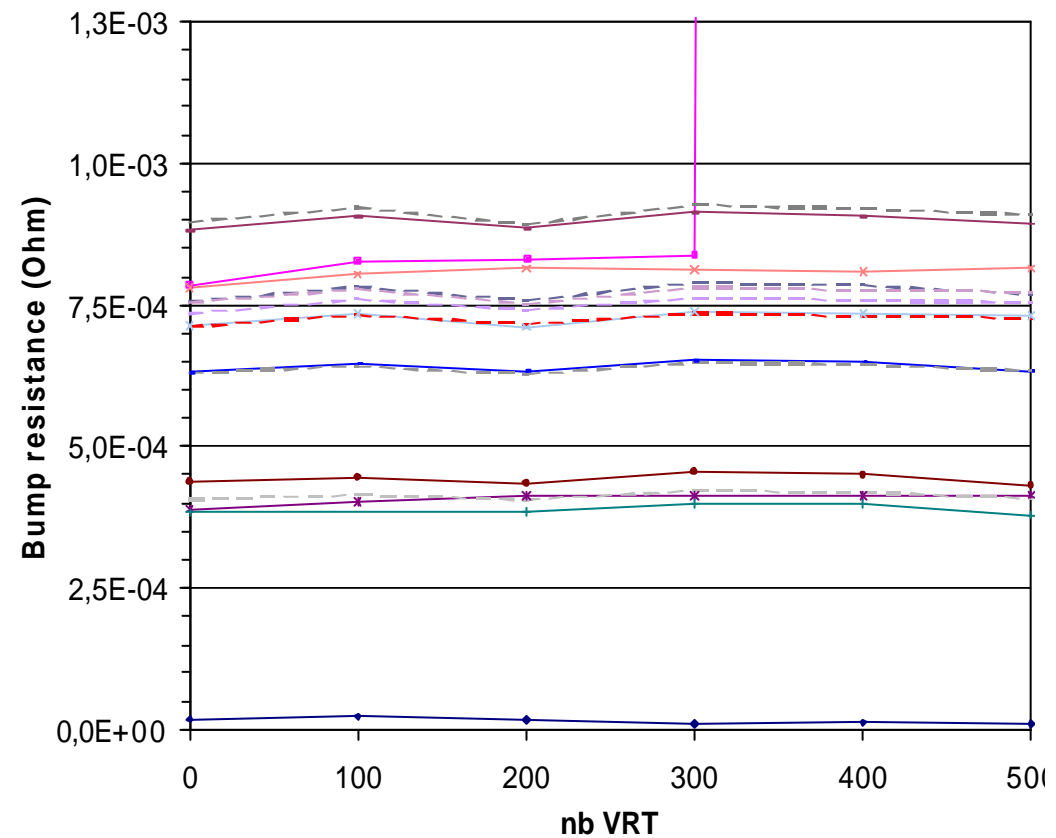
Thermal Cycling

On Alumina

with underfill



without underfill



Why Underfill ?

◆ Coefficient of Thermal Expansion Mismatch between die and substrate

🖱 high stress concentrated at the bump level

Chip	CTE @ 25°C (ppm/°C)	Substrate	CTE @ 25°C (ppm/°C)
GaAs	5.8	Alumina	5.25
Si	2.6	AlN	2.3

◆ Solution : Underfill

🖱 Inserting a curable liquid resin between the die and the substrate

➡ Spread the thermally induced stress over the entire package

🖱 ASP configuration

➡ Small bump height : 20 to 50 microns

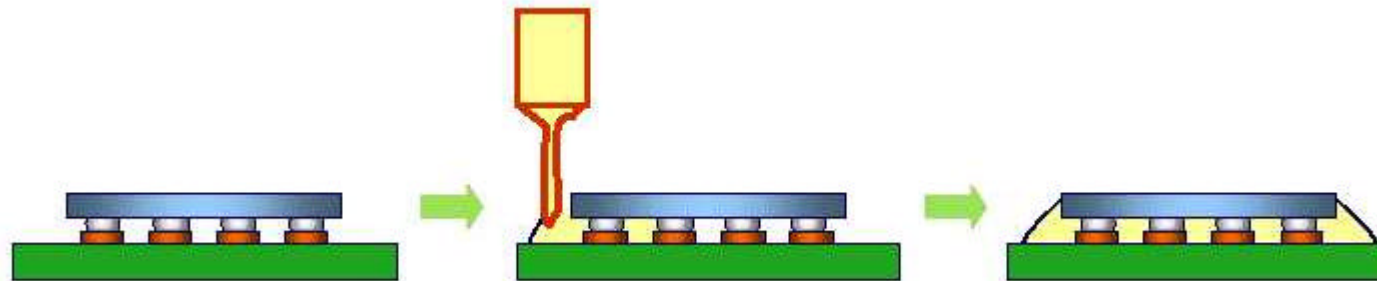
➡ Few bumps, mainly at the die periphery (i.e. high DNP)

➡ Die size : from 1x1 to 5x5 mm²

Underfill Solutions

◆ Capillary underfill

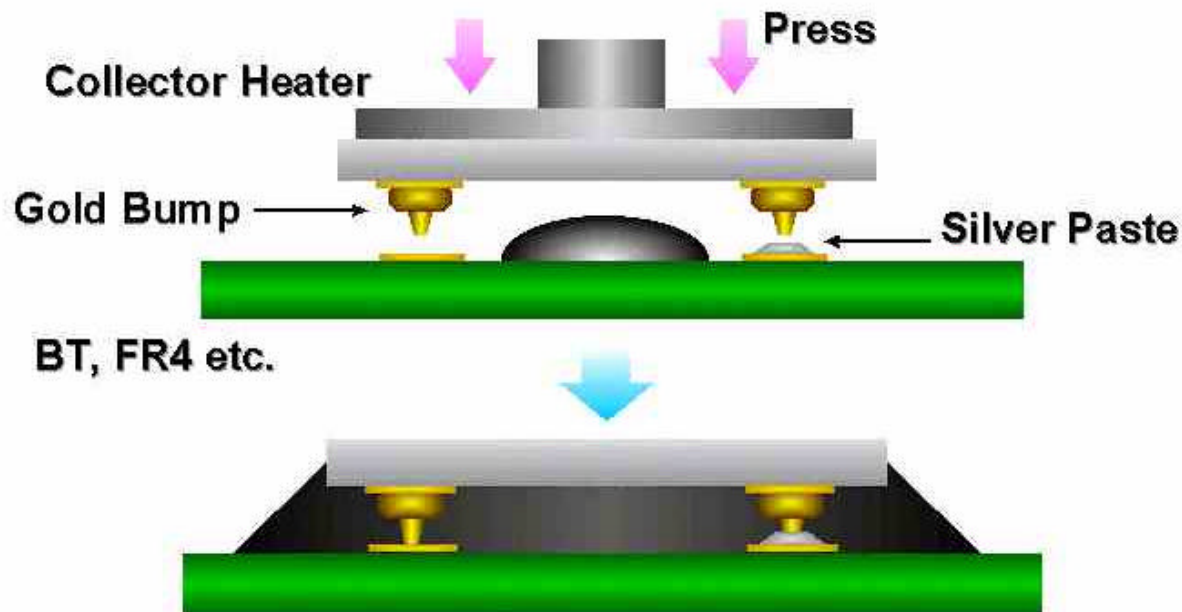
- 🖱 underfill dispensed near the edge of the chip
- 🖱 flow under the die by capillary action
- 🖱 cured when flow completed



- 🖱 most common type of commercial underfill
 - ➡ limit for high volume : time consuming (flow time + curing time)
 - ➡ new solutions under development

◆ "No Flow" underfill

- 🖱 underfill dispensed on substrate at the die location
- 🖱 chip is placed & pressed on the bump
- 🖱 flip chip assembly & underfill polymerisation at the same time
 - ➡ most of the time dedicated to solder bump
 - ➡ unfilled resin, so high CTE : source of fatigue
 - ➡ critical dispensing process ("floating chip")



🖱 "No Flow" underfill

- ➡ "Press Bump" Underfill
 - No flow for stub bumps
- ➡ products with or without fillers

Underfill ?

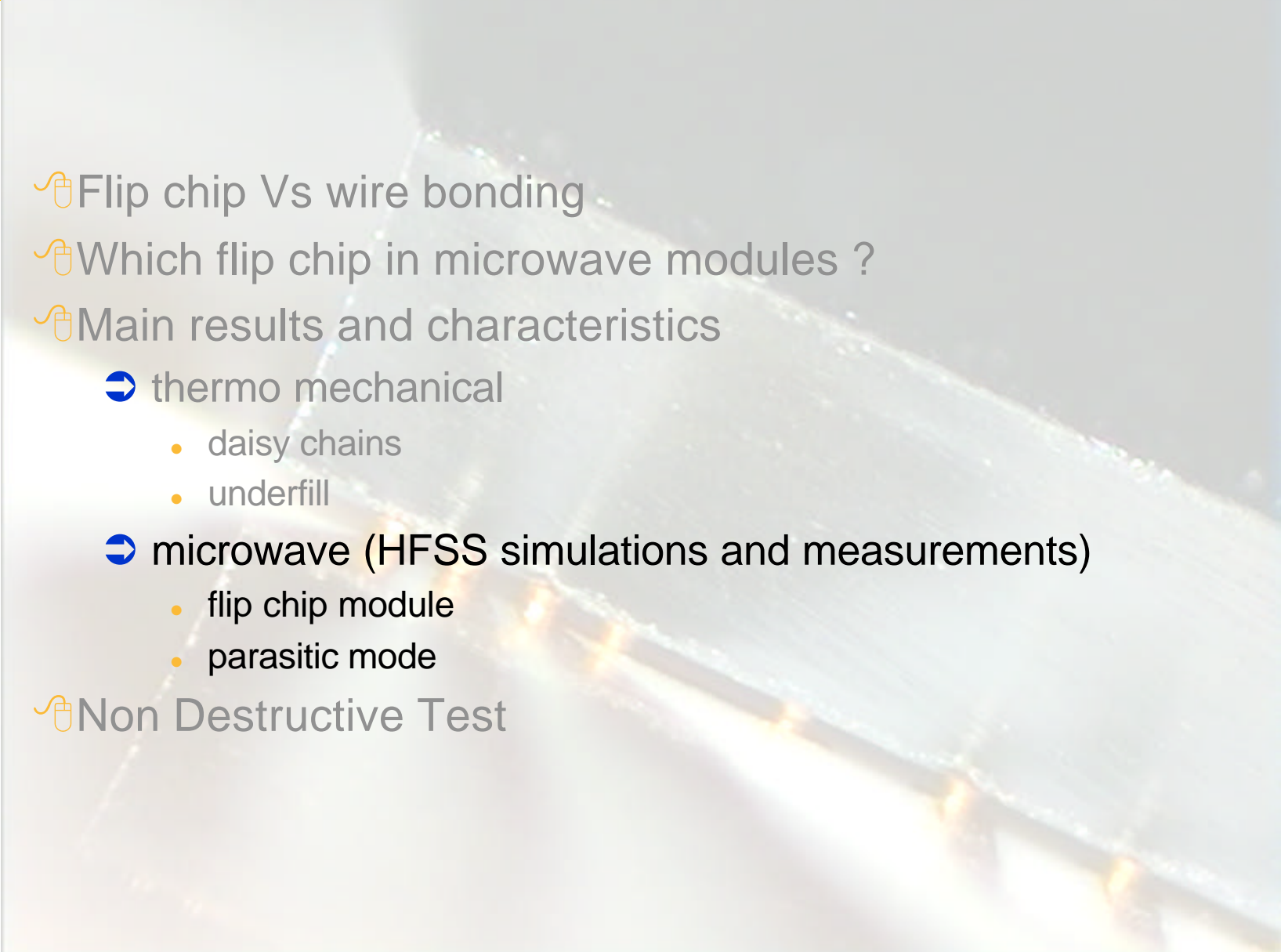
Pros : Fabrication et reliability

- ➔ Proven effectiveness for die dimensions up to 5x5mm et 5.5x4mm on AlN circuits
 - Thermal cycles [-55;+125°C] : 500-1000 OK
 - Storage at 125°C : 2000h OK
 - Better and stabilise good but imperfect assemblies (// pb for ex).
- ➔ Assembly secured
- ➔ Less severe control

Cons : Fabrication and electrical

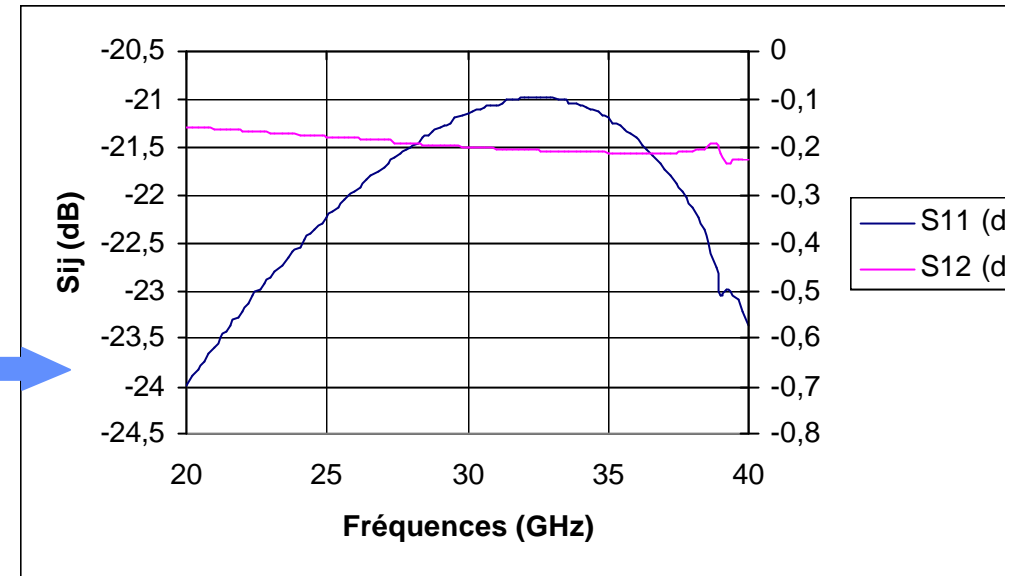
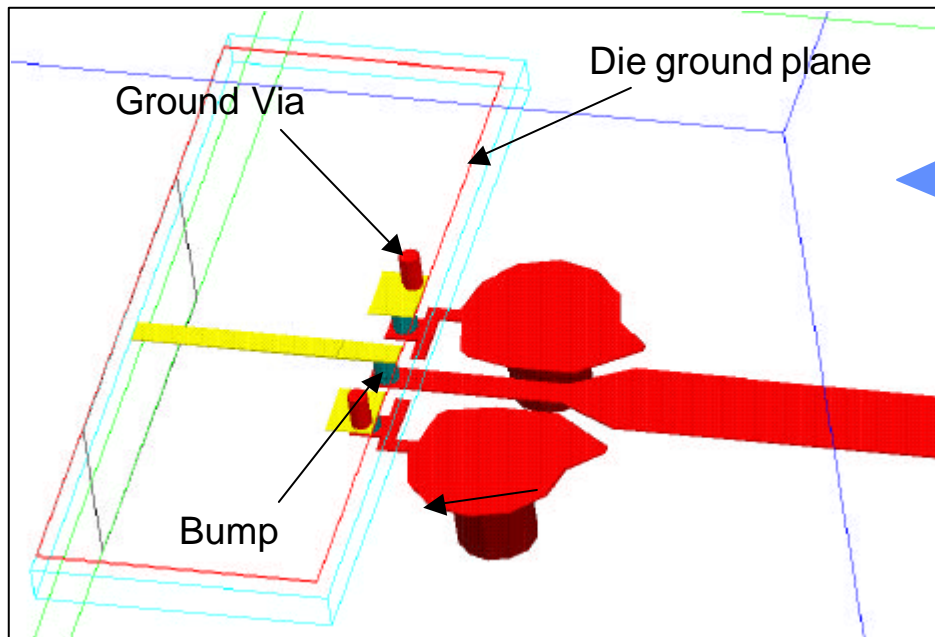
- ➔ New organic material (need evaluation and qualification)
- ➔ More fabrication steps
- ➔ More RF losses
- ➔ RF mismatch (frequency bandwidth gets lower)
 - MMIC design taken underfill into account (new library)
 - Or module design taken this frequency shift into account

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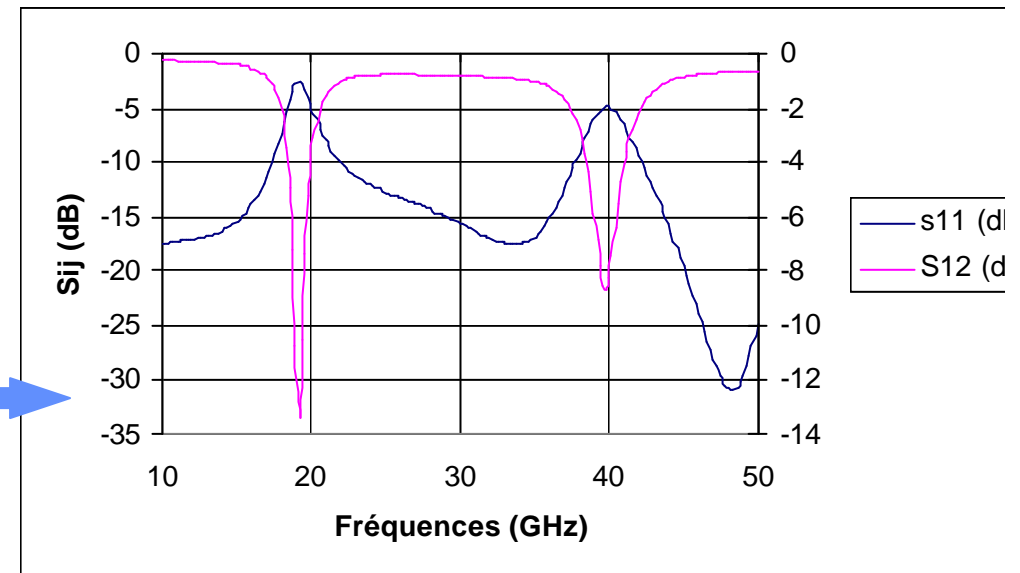
HFSS design

🖱️ optimisation of the flip chip transition



🖱️ Optimisation of the flip chip module (with 50 Ω line instead of MMIC function)

➡️ parasitic mode resonance localisation and management

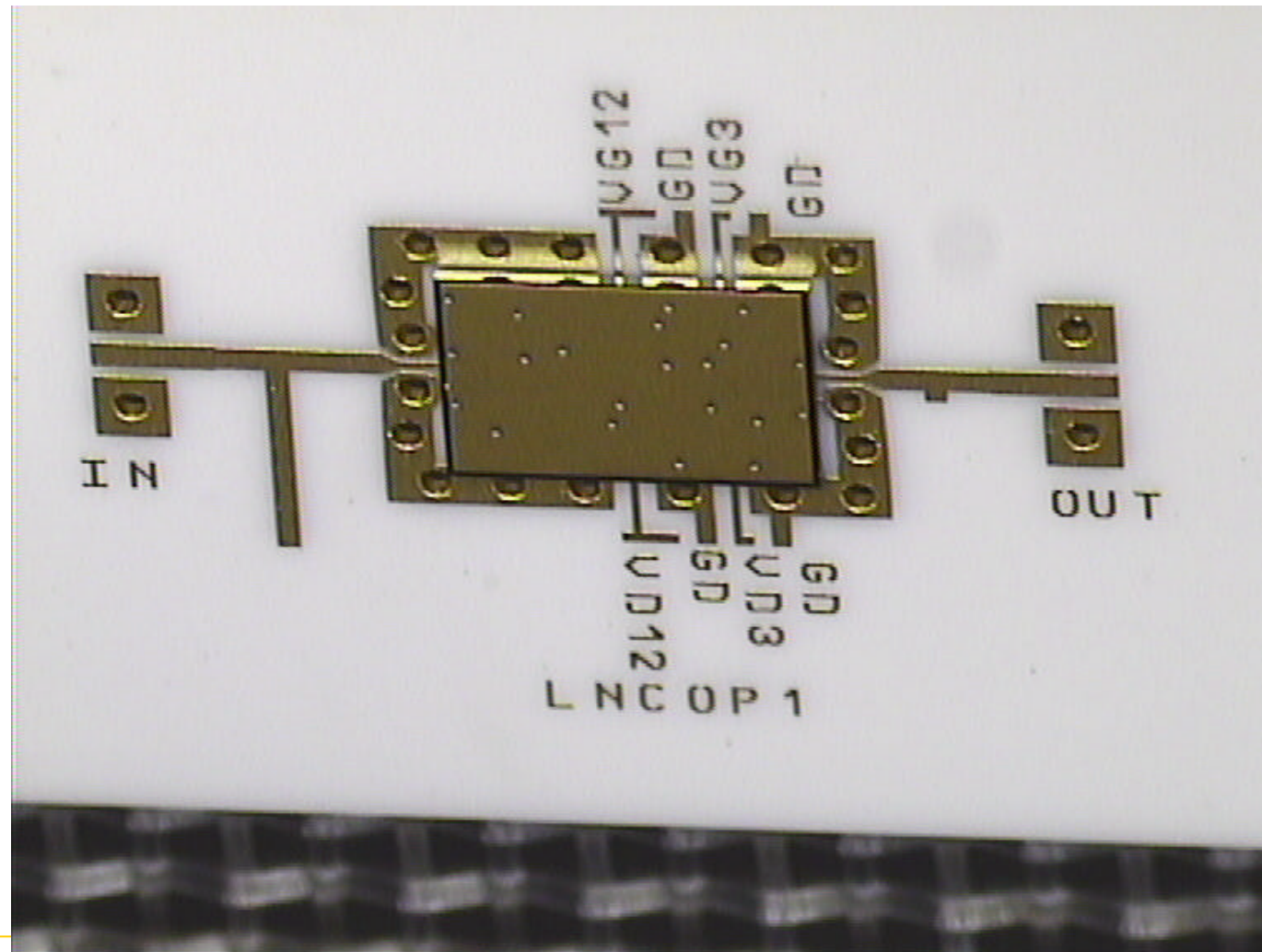
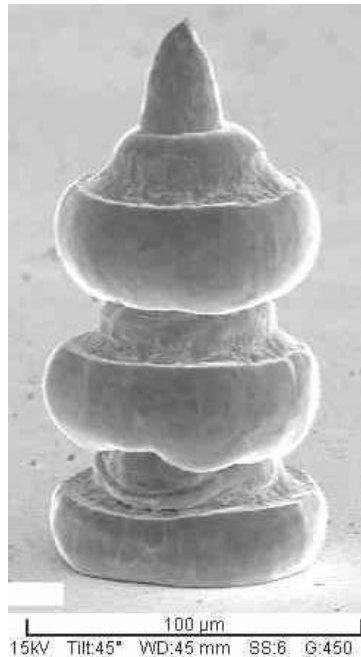


Parasitic mode : type of "Parallel Plate Mode"

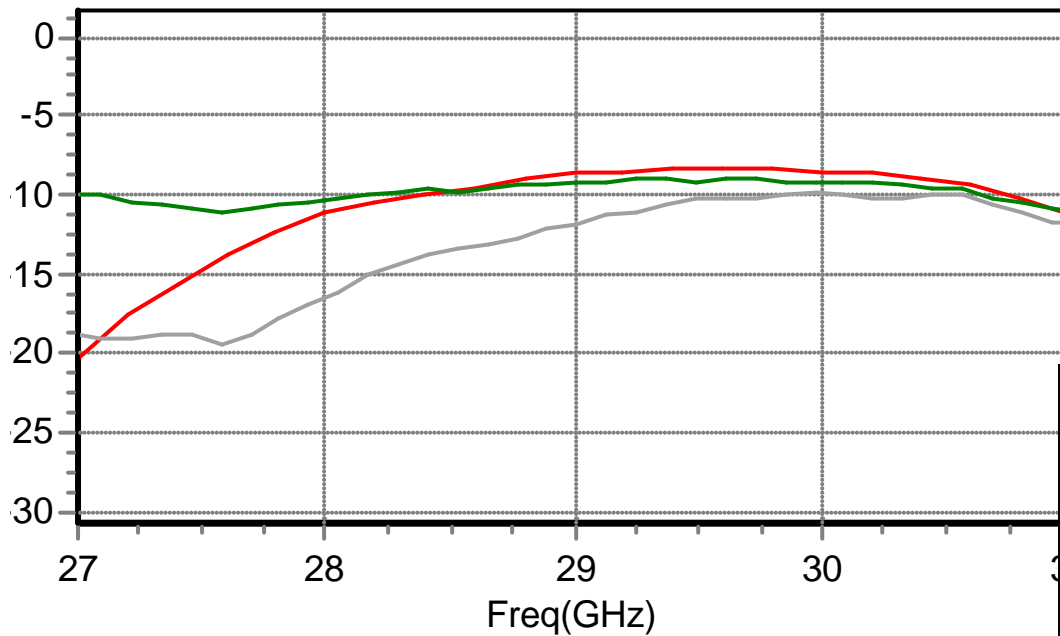
- 🖱 Coupling between MMIC and circuit ground planes
 - ➡ happens in main application with the chosen flip chip topology
- 🖱 Resonance frequency ➤ if :
 - ➡ die size ▼
 - ➡ bump height ➤
 - ➡ ground bump position and number ➤
 - ➡ underfill between die and substrate (global ϵ_r below the die ▼)
 - ➡ circuit thickness ➤
- 🖱 Solutions
 - ➡ HFSS simulations before circuit design -> possible to move this resonance frequency above active bandwidth
 - ➡ Take it into account in MMIC design
 - ➡ or other flip chip configuration
("Hot Via" or "Embedded transmission-lines (ETL)" topologies)

Flip Chip assembly of a 30GHz LNA

🖱️ LNAUM24A flip chip mounted on alumina circuit with HCM triple bumps



dB(S11)



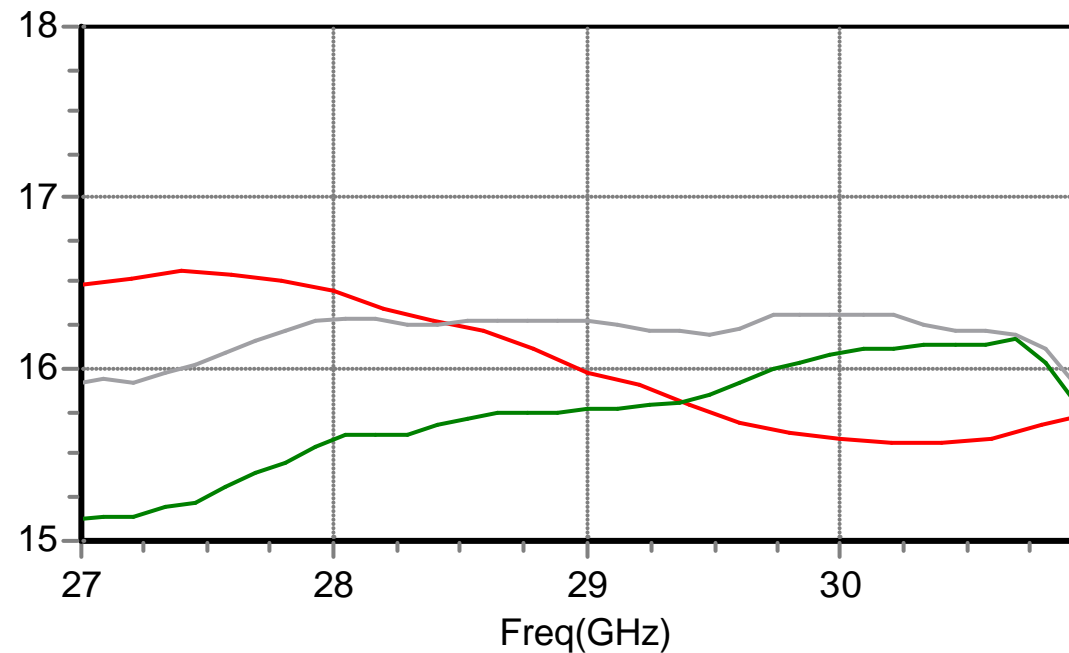
Measurement

Red - bare die

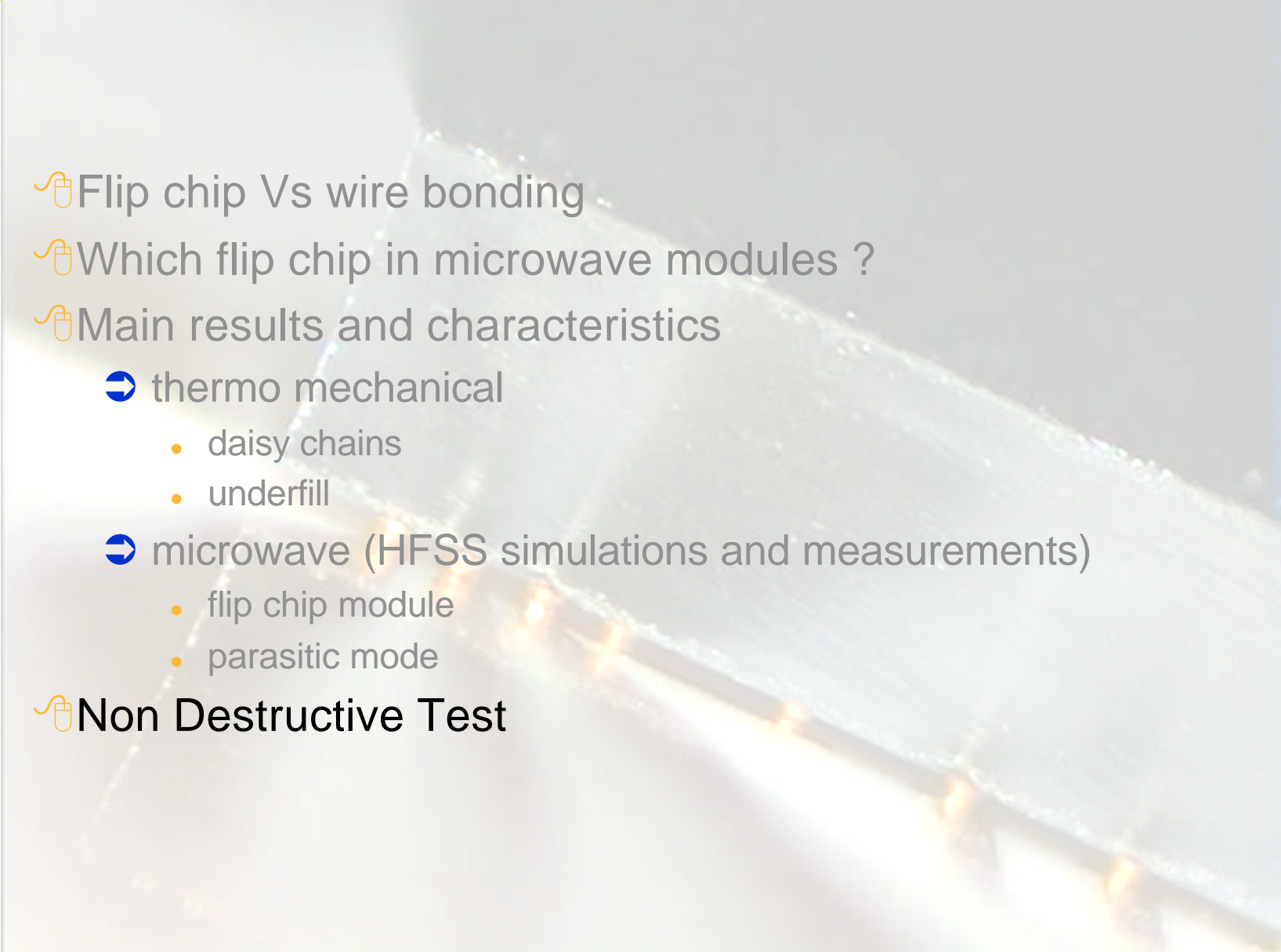
green - module with stub on alumina circuit

grey - module without stub on alumina circuit

dB(S21)



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Non Destructive Control

◆ What makes it to difficult...

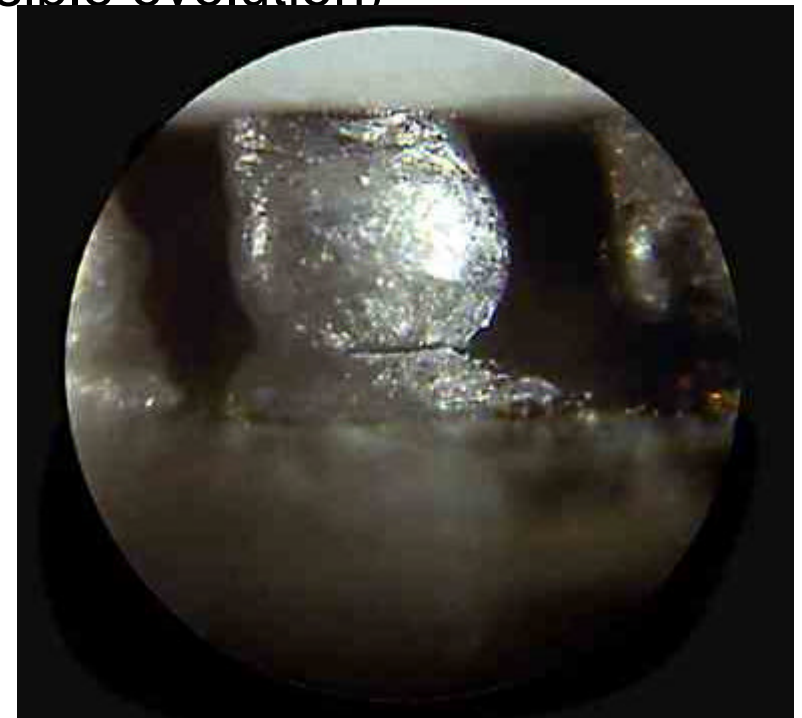
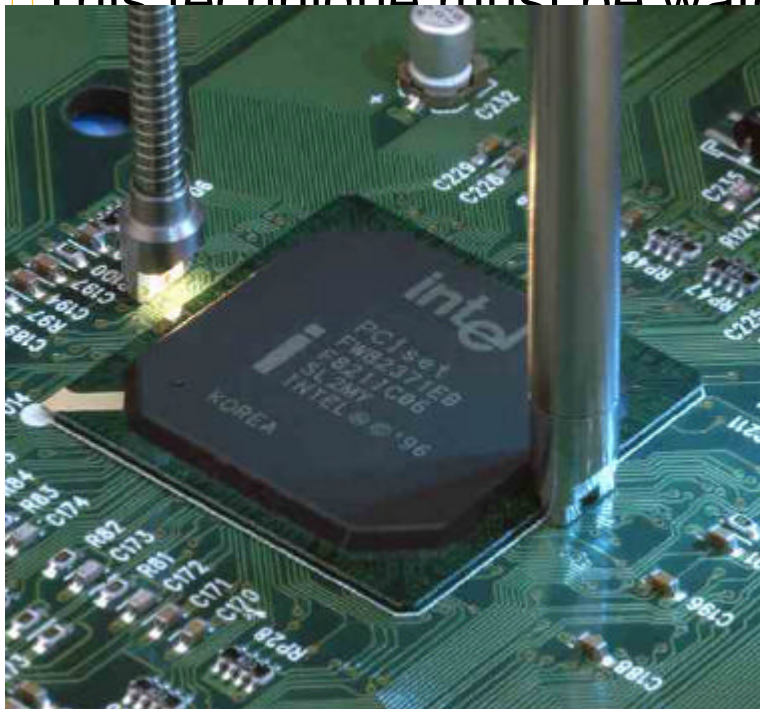
- 🖱 Bump dimensions -> $\sim 60\mu\text{m}$ ϕ and height
- 🖱 Bump position -> at die periphery
- 🖱 Default dimension and nature -> lack of adhesion of delaminations between two gold layers
- 🖱 Possible complexity of assembly (many metallic or different material layers)
- 🖱 Possible presence of underfill if CTE mismatch is too big

◆ Techniques under test

- 🖱 X Ray Microscopy - PHOENIX X-RAY / DAGE
- 🖱 Infra Red Microscopy - BARNES / QUANTUM FOCUS
- 🖱 Visual Inspection (not possible with underfill) - ERSA
- 🖱 Stress analysis with ESPI system - HIRONDELLE & ETTEMEYER

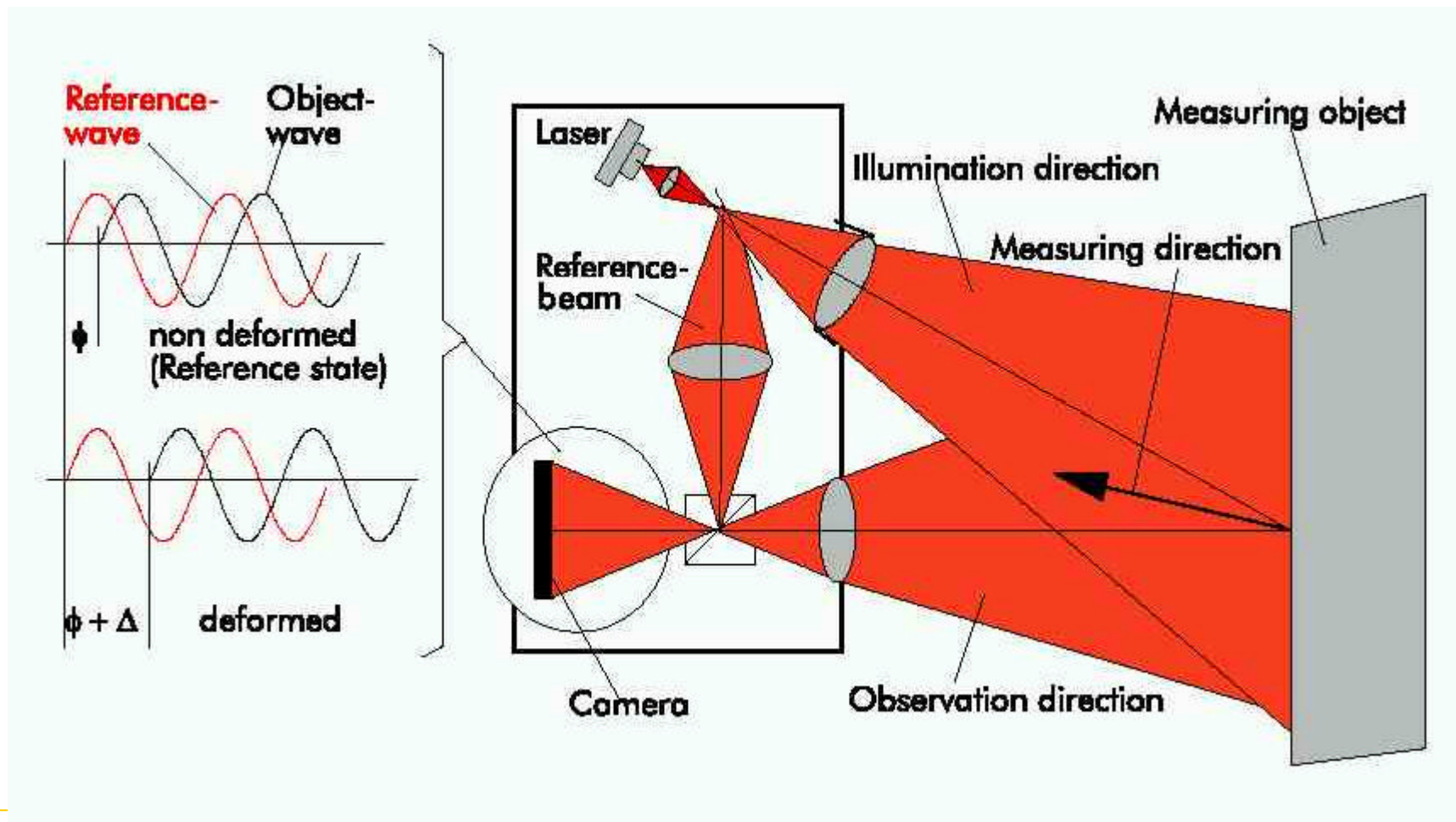
◆ Visual Inspection - Ersascope

- 🖱️ Very simple and direct technique
- 🖱️ adapted to BGAs
- 🖱️ but not enough accurate for bump and associated default dimensions
- 🖱️ This technique must be watched (possible evolution)



◆ ESPI technology of ETTEMEYER

- 🖱 European study HIRONDELLE (not finished)
- 🖱 stress and deformation analysis through interferometry

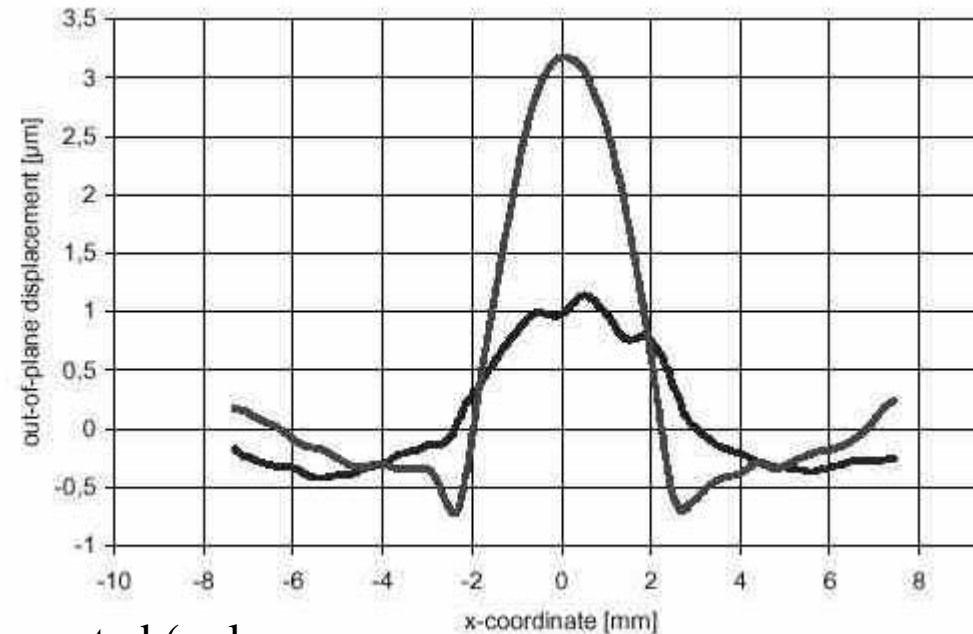


Flip Chip for microwave applications

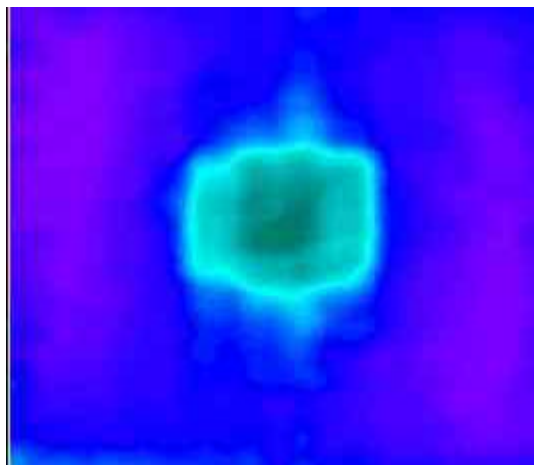
Control ?

3D-ESPI out of plane displacement measured between 25°C and 125°C on flip chip assembly of GaAs die on AlN substrate

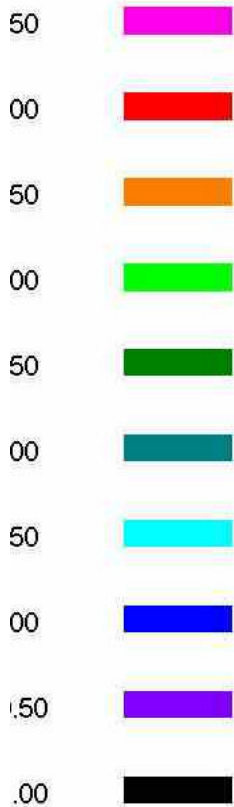
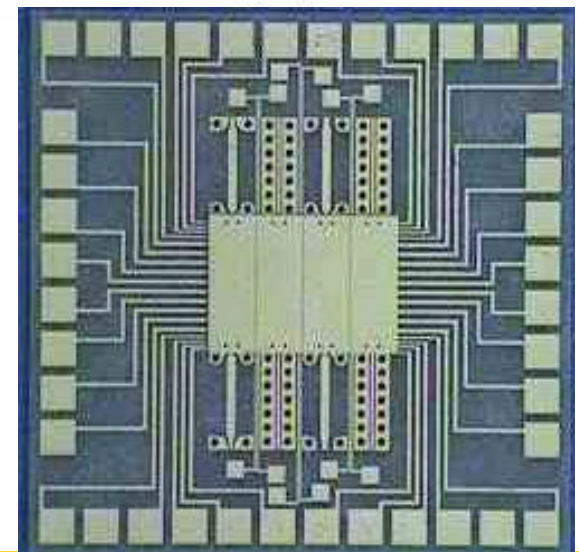
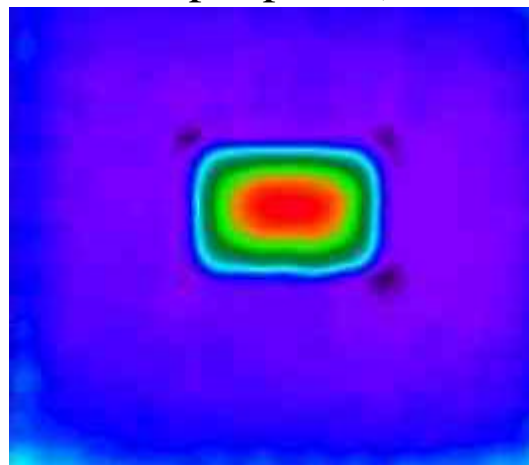
- ➡ further trials with less and smaller defects
- ➡ other ones with MMICs



All bumps connected



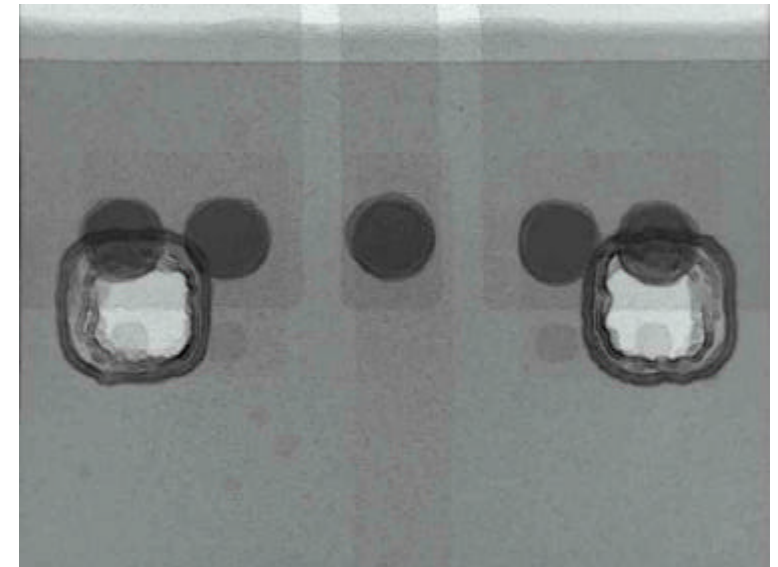
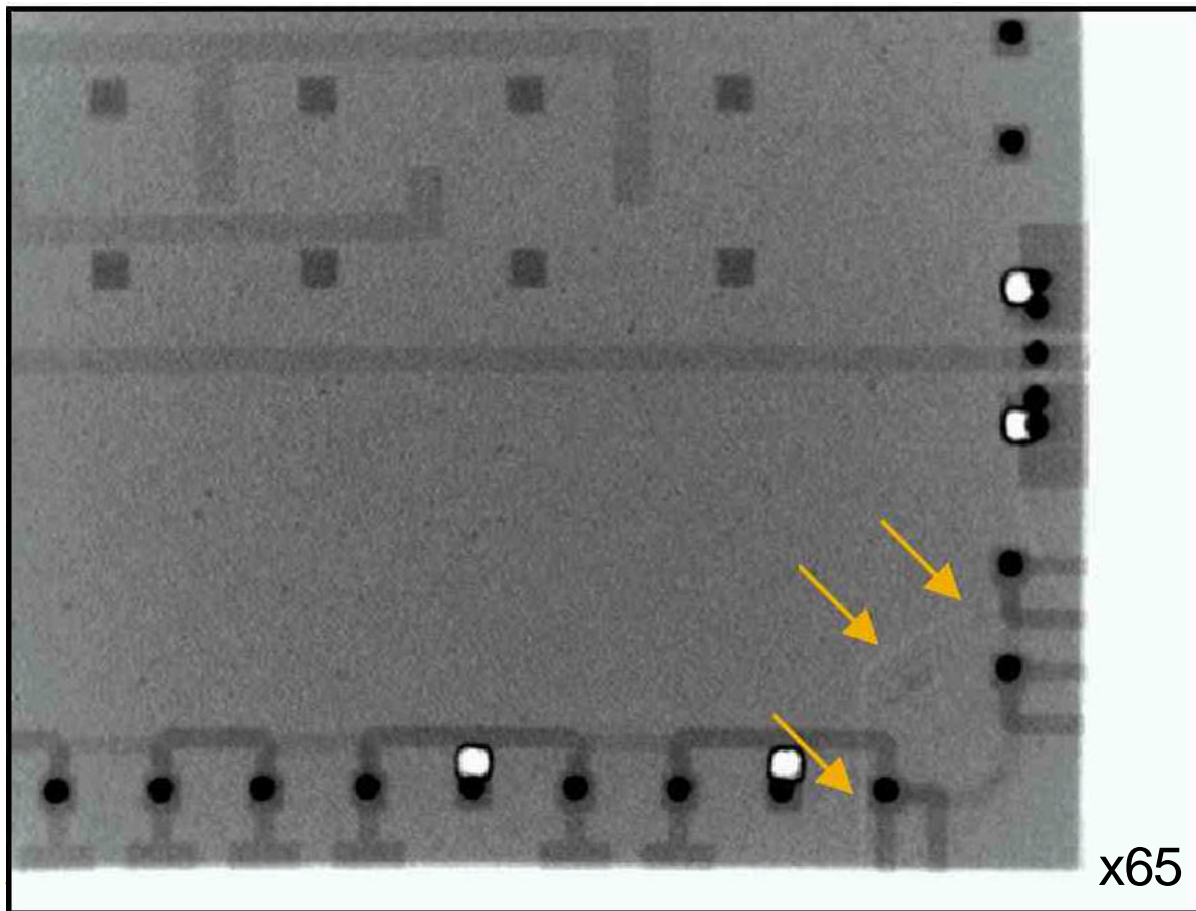
Half of bumps connected (only peripheral)



deformation [μm]

◆ X- ray microscopy (PHOENIX)

- ➔ nanofocus tube -> $0.3\mu\text{m}$ lateral resolution
- ➔ but defaults $<1\mu\text{m}$ detection mainly depends on used detector contrast
- ➔ could not see any default on bumps

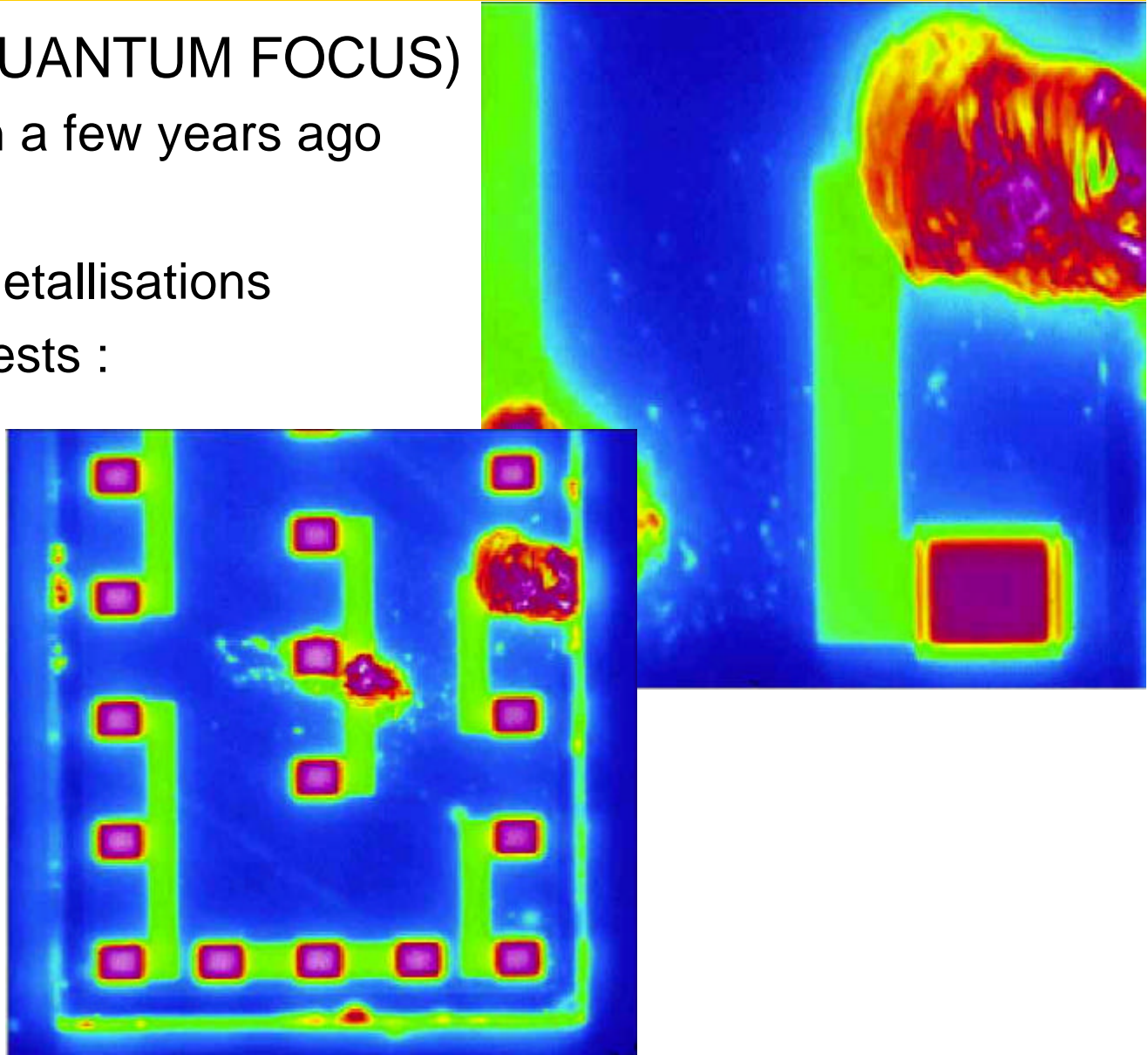


Flip Chip for microwave applications

Control ?

◆ Infra Red Microscopy (QUANTUM FOCUS)

- ☞ Much more precise than a few years ago
- ☞ good resolution
- ☞ but bumps hidden by metallisations
- ☞ some further possible tests :
 - ➔ Temperature pulse
 - ➔ Faster acquisition



Proposed Solution - Sampling

- ◆ Widely used elsewhere but could it be applied to Space equipment fabrication ?

🖱 application domains :

- ➡ when control is destructive
- ➡ when control takes too long
- ➡ when control is too expensive

🖱 Goal

- ➡ decide whether or not the lot is acceptable
- ➡ not for quality estimation

🖱 between 100% and 0% control

- ➡ but with a good knowledge of error probability
- ➡ several kinds of Acceptance Sampling Plans

◆ Conditions

- 🖱 process must already be qualified
- 🖱 measurement precision must be known -> error due to :
 - ➡ different kind of samples (part to part variation),
 - ➡ operator (reproducibility)
 - ➡ and error inherent in measurement tool (repeatability)

◆ Which acceptance or rejection criteria ?

- ➡ Can some defaults be accepted ? (depending on default nature or position)
- ➡ look for norms depending on chosen control test.

◆ Which control for flip chip inspection ?

- 🖱 Cuts and SEM inspection (most precise)
- 🖱 Shear tests (easiest)
- 🖱 Pull tests (maybe better results than shear tests but much more difficult to implement)